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/G. Nagesh Rao/ (01/26/2010)

**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1792**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Makoto IIDA

Group Art Unit: 1792

Application No.: 10/586,476

Examiner: G. RAO

Filed: July 18, 2006

Docket No.: 128768

For: A METHOD FOR PRODUCING SEMICONDUCTOR WAFERS AND A SYSTEM  
FOR DETERMINING A CUT POSITION IN A SEMICONDUCTOR INGOT

**REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the October 27, 2009 Office Action, and in consideration of the January 13, 2010 personal interview, reconsideration of the rejection is respectfully requested in light of the following remarks. Claims 9-26 are pending in this application.

Applicant appreciates the courtesies shown to Applicant's representative by Examiner Rao during the January 13, 2010 personal interview. Applicant's separate record of the substance of the interview is incorporated into the following remarks.

The Office Action acknowledges the claim for foreign priority under 35 U.S.C. §119, but asserts that Applicant is required under 35 U.S.C. §119(b) to file a certified copy of the foreign priority document. The current application is a national phase of international application PCT/JP2005/000641, filed January 20, 2005. Applicant complied with PCT Rule